

PATENT  
0397-0404P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant:	H. TAKEUCHI et al.	Conf.:	4024
Appl. No.:	09/541,089	Group:	1762
Filed:	March 31, 2000	Examiner:	M. PADGETT
For:	PLASMA PROCESSING METHOD		

LARGE ENTITY TRANSMITTAL FORM  
FOR REPLY AFTER FINAL UNDER 37 C.F.R. § 1.116

**-BOX- AF**

Assistant Commissioner for Patents  
Washington, DC 20231

February 6, 2003

Sir:

Transmitted herewith is a reply in the above-identified application.

- ☐ The enclosed document is being transmitted via the Certificate of Mailing provisions of 37 C.F.R. § 1.8.
- ☐ The enclosed document is being transmitted via facsimile.

The fee has been calculated as shown below:

	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR		PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL	8	-	20	=	0	\$ 18	\$0.00
INDEPENDENT	1	-	3	=	0	\$ 84	\$0.00
<input type="checkbox"/> FIRST PRESENTATION OF A MULTIPLE DEPENDENT CLAIM						\$280	\$0.00
						TOTAL	\$0.00

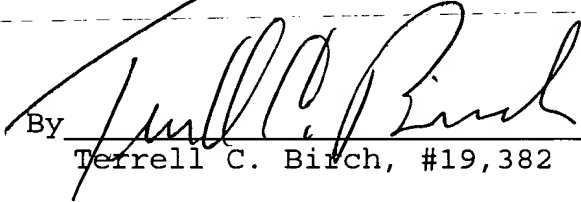
- ☐ Petition for ( ) month(s) extension of time pursuant to 37 C.F.R. §§ 1.17 and 1.136(a). \$0.00 for the extension of time.
- ☒ No fee is required.
- ☐ Check(s) in the amount of \$0.00 is(are) enclosed.
- ☐ Please charge Deposit Account No. 02-2448 in the amount of \$0.00. This form is submitted in triplicate.


If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fees required under 37 C.F.R. §§1.16 or 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

By

  
Terrell C. Birch, #19,382

  
TCB/CMV/jdm  
0397-0404P

P.O. Box 747  
Falls Church, VA 22040-0747  
(703) 205-8000

Attachment(s)

(Rev. 09/30/02)



RECEIVED  
FEB 10 2003  
TC 1700

11B  
2/13/03  
BOX AF  
REPLY UNDER  
37 C.F.R. § 1.116  
EXPEDITED PROCEDURE

PATENT  
0397-0404P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: H. TAKEUCHI et al. Conf.: 4024  
Appl. No.: 09/541,089 Group: 1762  
Filed: March 31, 2000 Examiner: M. PADGETT  
For: PLASMA PROCESSING METHOD

REPLY AFTER FINAL UNDER 37 C.F.R. § 1.116

**BOX AF**

Assistant Commissioner for Patents  
Washington, DC 20231

February 6, 2003

Sir:

In reply to the Office Action mailed November 7, 2002, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

**IN THE CLAIMS:**

Please amend the claims as follows:

- 500  
C<sub>1</sub>  
B
1. (Twice Amended) A plasma processing method comprising:  
supporting a substrate to be opposed to an electrode;  
setting the plasma processing gas to pressure P(Torr) where P(Torr) satisfies the following relationship  
$$2 \times 10^{-7} (\text{Torr/Hz}) \times f(\text{Hz}) \leq P(\text{Torr}) \leq 500 (\text{Torr})$$